

Figure 1. Schematic of the PEALD reactor (left) and the PEALD process sequence (right).

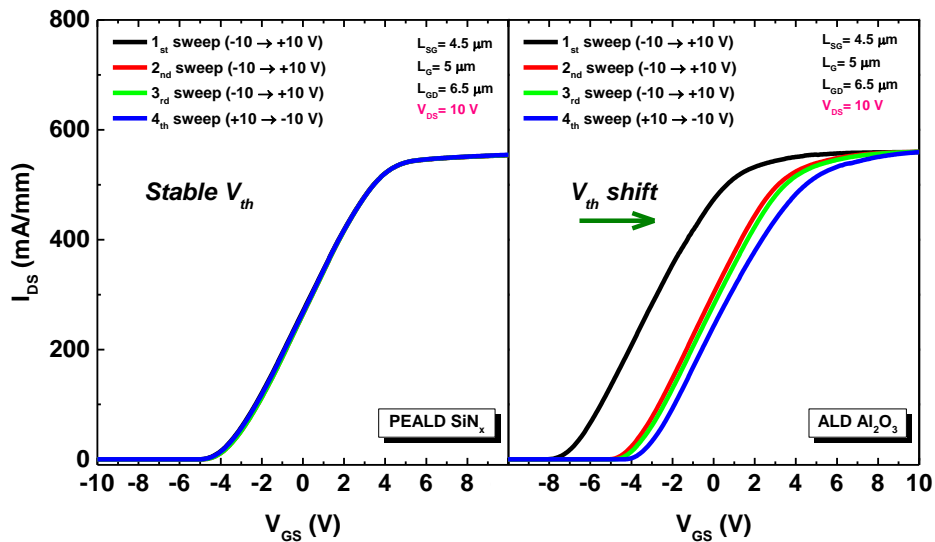


Figure 2. Comparison of the I_{DS} - V_{GS} characteristics of MIS-HEMTs.

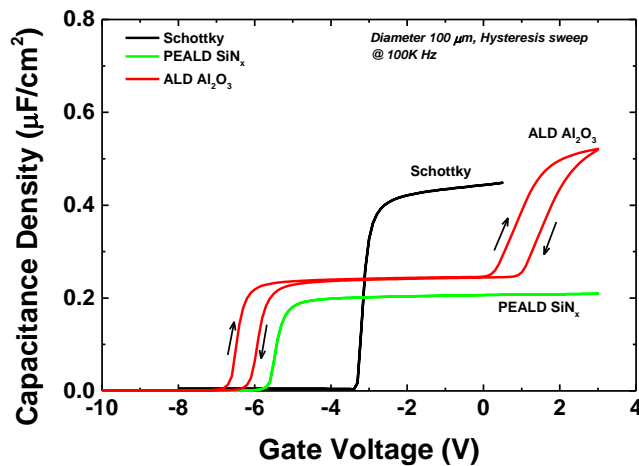


Figure 3. Comparison of the C-V characteristics of capacitors in HEMT samples.